



PCT/JP2003/012946
-filed October 9, 2003

Re: Application of Tsunehisa NAMIKI, Toshihide IEKI, Hideo KURASHIMA,
Hajime INAGAKI, Akira KOBAYASHI, and Koji YAMADA
METHOD OF FORMING A METAL OXIDE FILM AND MICROWAVE
POWER SOURCE DEVICE USED FOR THE ABOVE METHOD
Assignee: TOYO SEIKAN KAISHA, LTD.
Our Ref: Q87270

Dear Sir:

The following documents and fees are submitted herewith in connection with the above application for the purpose of entering the National stage under 35 U.S.C. §371 and in accordance with the Patent Cooperation Treaty:

- ☒ an English translation of the International Application.
- ☒ nineteen (19) sheets of drawings (Figs. 1-25).
- ☒ Notification Concerning Submission or Transmittal of Priority Document
- ☒ an Information Disclosure Statement and a copy of the ISR.
- ☒ a PTO/SB/08 A & B (modified) listing the ISR references.
- ☒ **it is expressly requested that the national stage of processing be commenced immediately in accordance with 35 U.S.C. § 371(f)**

A copy of the Declaration and Power of Attorney, and a copy of the Assignment will be submitted at a later date.

In addition to the documents submitted herewith, it is assumed that copies of the International Application, the International Search Report and cited references, the International Preliminary Examination Report, and any Articles 19 and 34 amendments as required by §371(c) will be supplied directly by the International Bureau, but if further copies are needed, the undersigned will undertake to provide them upon request.

The Government filing fee is calculated as follows:

Total claims	26 - 20 = 6 x \$50.00 = \$300.00
Independent claims	3 - 3 = 0 x \$200.00 = \$0.00
Base Fee	\$300.00
Search Fee*	\$400.00
Examination Fee*	\$200.00

**Sughrue**

SUGHRUE MION, PLLC

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TOTAL FEE\$1200.00

* The international search fee for all claims was not paid to the USPTO, as the ISA, but the ISR is being submitted herewith.

A check for the statutory filing fee of \$1200.00 is attached. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this transmittal letter is attached.

Priority is claimed from:

<u>Country</u>	<u>Application No</u>	<u>Filing Date</u>
Japan	2002-295908	October 9, 2002
Japan	2003-112136	April 16, 2003
Japan	2003-116301	April 21, 2003

Respectfully submitted,

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WASHINGTON OFFICE

23373

CUSTOMER NUMBER

Date: April 6, 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of
NAMIKI, Tsunehisa et al.
Application No. PCT/JP2003/012946
International Filing Date: October 9, 2003
For: Method of forming a metal oxide film and microwave
power source device used for the above method

VERIFICATION OF TRANSLATION

Honorable Commissioner of Patents and Trademarks
Washington, D.C. 20231

KEIJI TOKIEDA residing at 2-20-204, Kaitori 2-chome,
Tama-shi, Tokyo, Japan, declares:

(1) That I know well both the Japanese and English
languages;

(2) that I translated the International
Application No. PCT/JP2003/012946 from Japanese to
English;

(3) that the attached English translation is a
true and correct translation of the International
Application No. PCT/JP2003/012946 to the best of my
knowledge and belief; and

(4) that all statements made of my own knowledge
are true and that all statements made on information
and belief are believed to be true, and further that
these statements are made with the knowledge that
willful false statements and the like are punishable
by fine or imprisonment, or both, under 18 USC 1001,
and that such false statements may jeopardize the
validity of the application or any patent issuing
thereon.

Date: March 22, 2005


Keiji Tokieda